

Timing performance of 3D pixel detectors

Gian-Franco Dalla Betta^{1,2} (gianfranco.dallabetta@unitn.it)

{ ¹ University of Trento, ² TIFPA INFN }, Trento, Italy



Sestri Levante, 16-20 October 2023

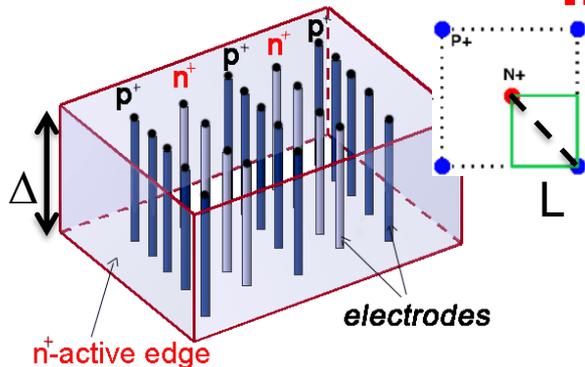
Outline

- Introduction: 3D Sensors
- Timing with 3D sensors
- Results:
 - 3D-columnar sensors
 - 3D-Trenched sensors (TIMESPOT)
- Ongoing developments
- Conclusions

Introduction: 3D Sensors

S. Parker et. al. NIMA 395 (1997) 328

Electrode distance (L) and active substrate thickness (Δ) are decoupled $\rightarrow L \ll \Delta$ by layout



High radiation hardness at relatively low voltage (power)

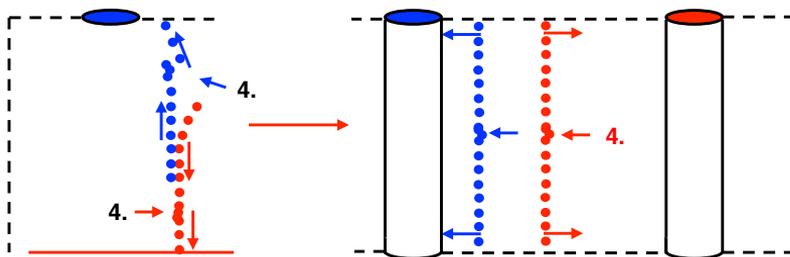
ADVANTAGES:

- Low depletion voltage (low power diss.)
- Short charge collection distance:
 - Fast response
 - Less trapping probability after irr.
- Lateral drift \rightarrow cell “shielding” effect:
 - Lower charge sharing
 - Low sensitivity to magnetic field
- Active edges

DISADVANTAGES:

- Non uniform spatial response (electrodes and low field regions)
- Higher capacitance with respect to planar ($\sim 3x$ for $\sim 150 \mu\text{m}$ thickness)
- Complicated technology (cost, yield)

Timing: Planar vs 3D

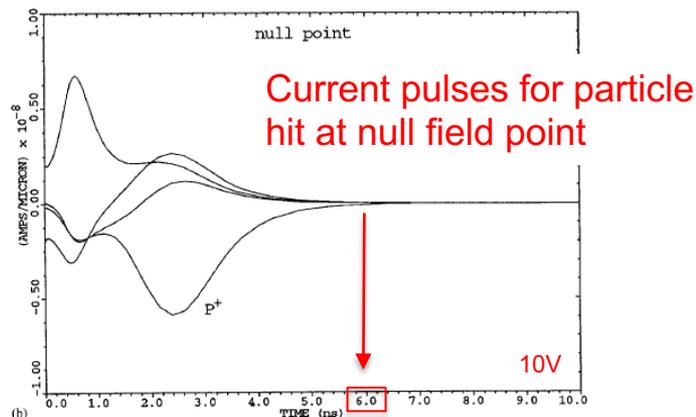
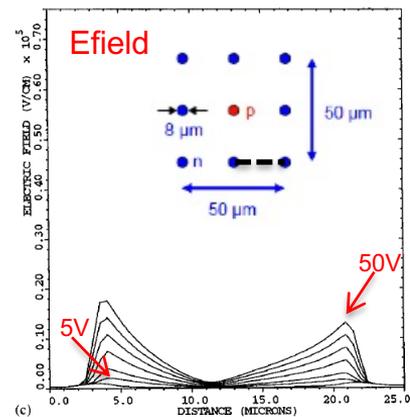
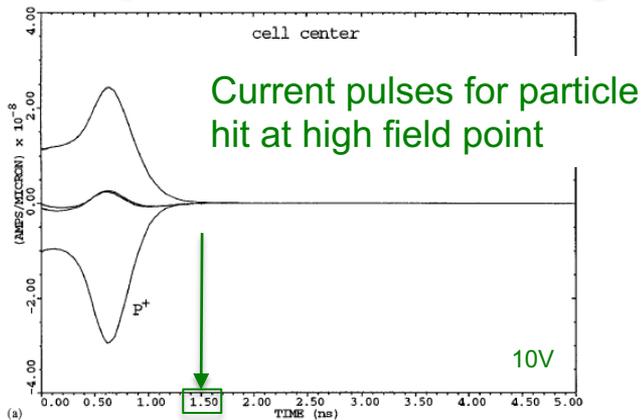
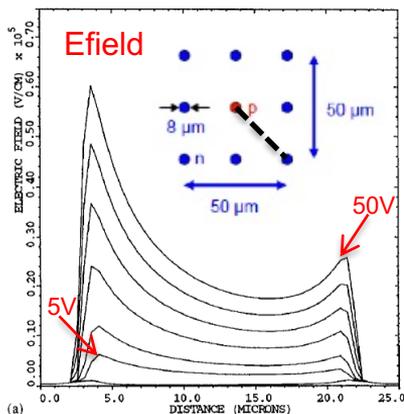


S. Parker et al. IEEE
TNS 58(2) (2011) 404

1. 3D lateral cell size can be **smaller** than wafer thickness, so
2. in 3D, field lines end on **electrodes of larger area**, so
3. most of the signal is induced when the charge is close to the electrode, so planar signals are **spread out in time** as the charge arrives, whereas
4. Landau fluctuations along track arrive **sequentially** and may cause secondary peaks

1. **shorter collection distance**
2. **higher average fields for any given maximum field (price: larger electrode capacitance)**
3. **3D signals are concentrated in time as the track arrives**
4. **Landau fluctuations (delta ray ionization) arrive nearly simultaneously**

Null field points and delayed signals

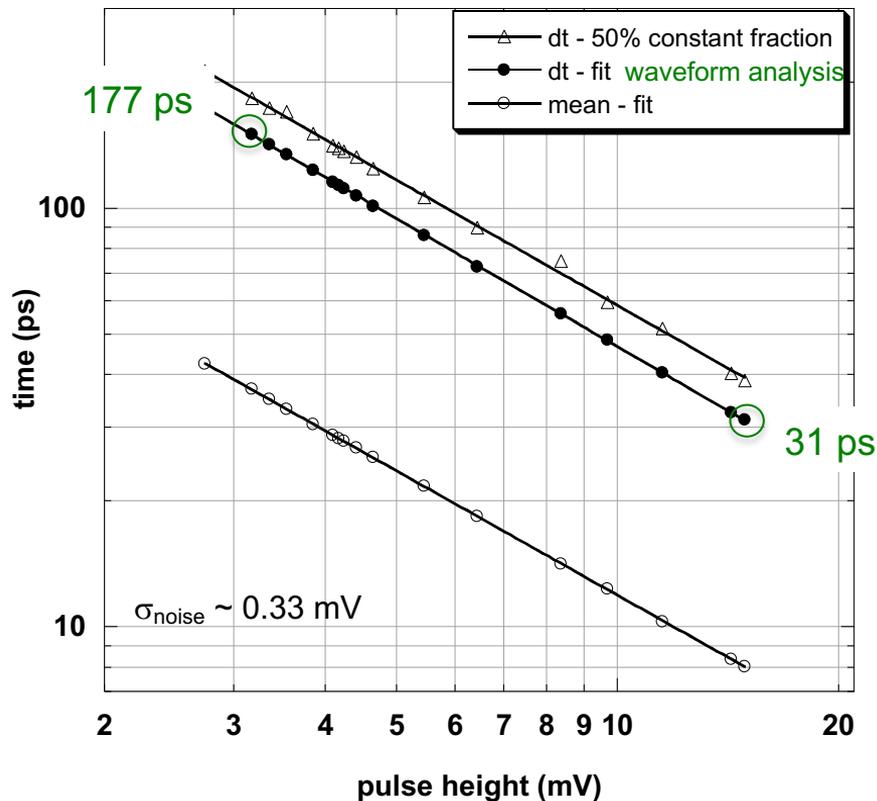
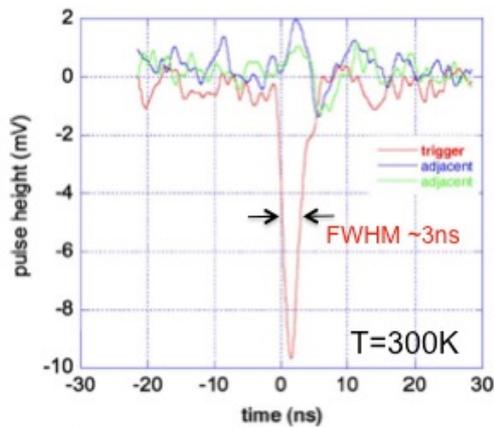
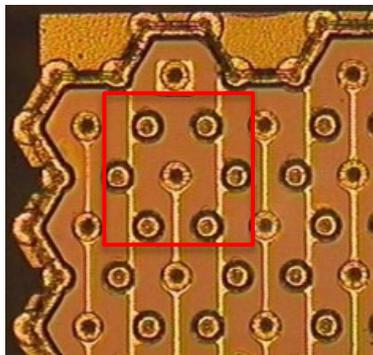


S. Parker et al.
NIMA395 (1997) 328

- 3D structure can potentially yield very fast signals of the order of 1 ns
- But electric field is not uniform, and null field points are present: signals are delayed due to initial diffusion
- Moreover, electrodes are (almost) dead regions
- These aspects can be improved with dedicated designs

An early study of speed with 3D

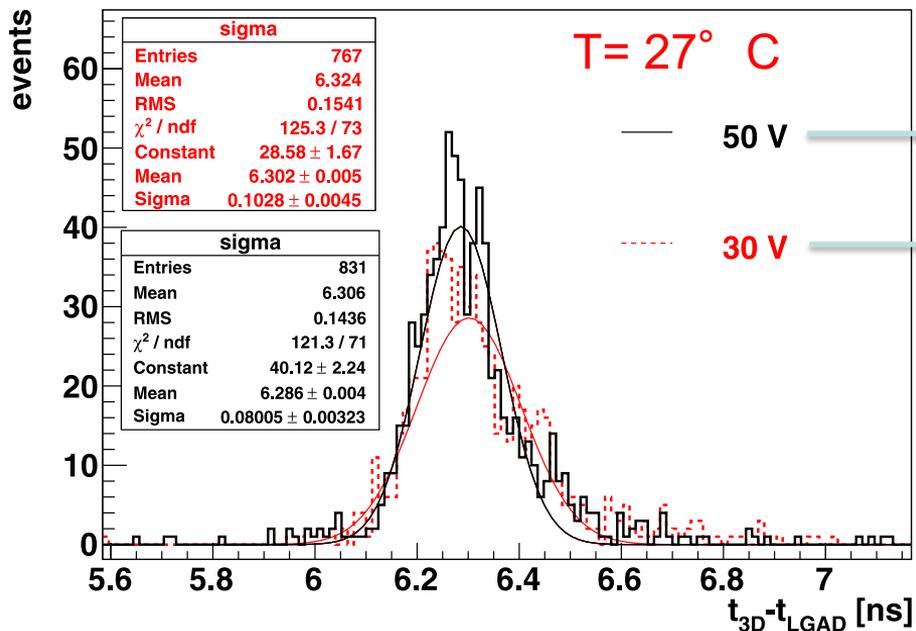
S. Parker et al. IEEE
TNS 58(2) (2011) 404



- Initially tested with ^{90}Sr source on hex-cell strip 3D's from SNF ($L=50 \mu\text{m}$) & fast current amplifier
- Despite several non-idealities (e.g., large capacitance, low bias, uncollimated source), promising results were obtained

Increasing interest in 3D pixels for timing

- CNM 50x50 μm^2 single cells DS-3D (230 and 285 μm thick) tested by several groups
- Beta source setups, with LGADs as reference
- Discrete amps + CFD + fast oscilloscopes

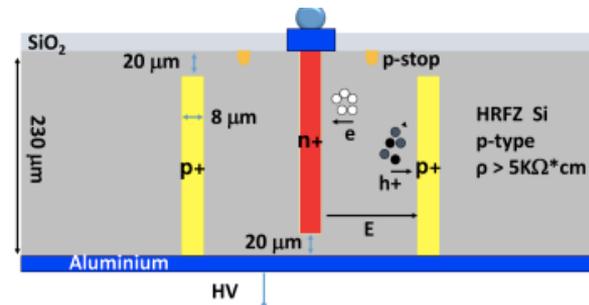
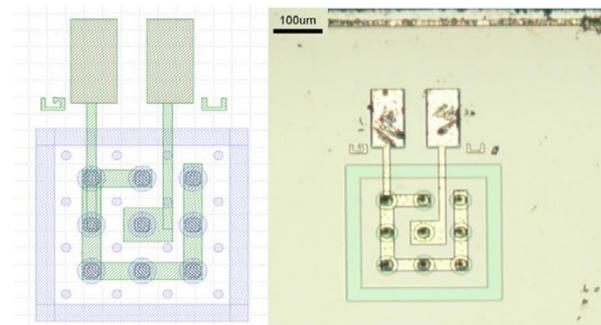


$\sigma_{\text{wf}} = 58 \pm 5 \text{ ps}$

$\sigma_{3\text{D}} = 75 \text{ ps}$

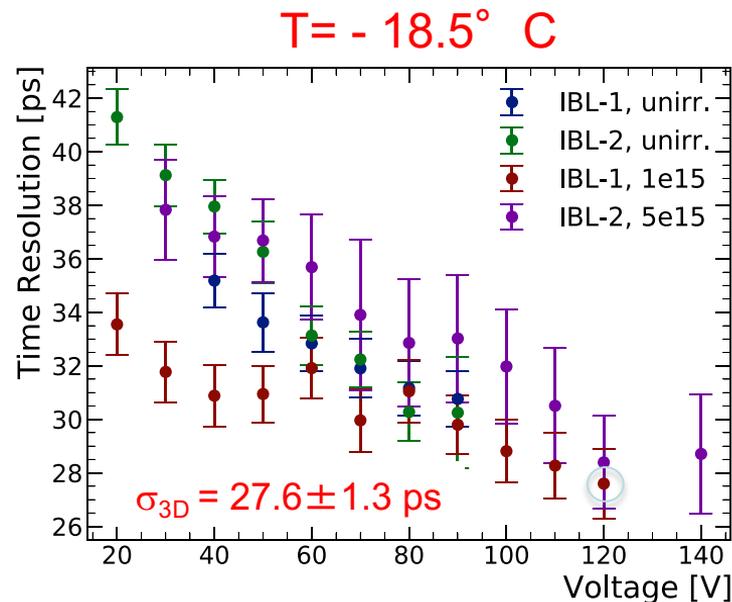
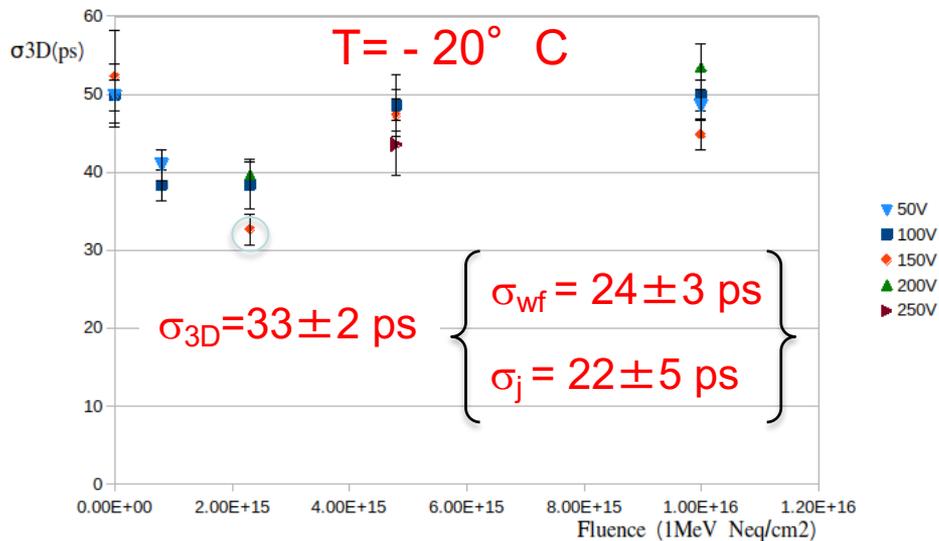
$\sigma_{3\text{D}} = 98 \text{ ps}$

$\sigma_{\text{wf}} = 81 \pm 6 \text{ ps}$



Neutron irradiated samples

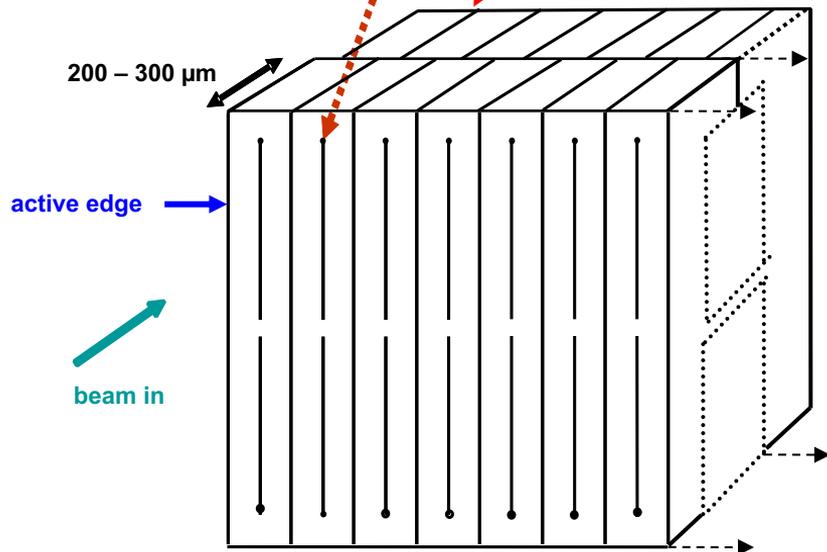
- Same type of test structures from CNM, very similar beta source setups
- Best result ~ 27 ps timing resolution



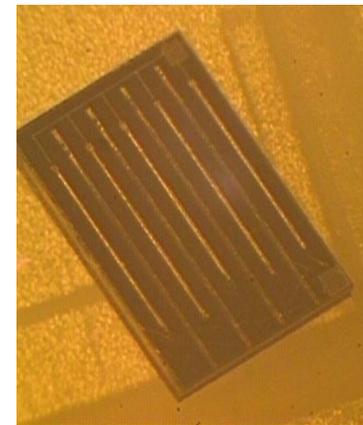
3D Trenched-electrode sensors

signal electrodes with contact pads to readout

next section offset so signal electrodes do not line up



Schematic diagram of multiple plane arrangement in an active-edge 3D trench-electrode detector. Other offsets ($\frac{1}{3}$, $\frac{2}{3}$, 0, $\frac{1}{3}$, $\frac{2}{3}$..etc.) may also be used.



S. Parker et al.
IEEE TNS 58(2) (2011) 404

Benefits from trench electrodes

- High average field / peak field
- More uniform electric and weighting field distributions

Possible issues

- Fabrication complexity
- Higher electrode capacitance
- Larger dead volumes

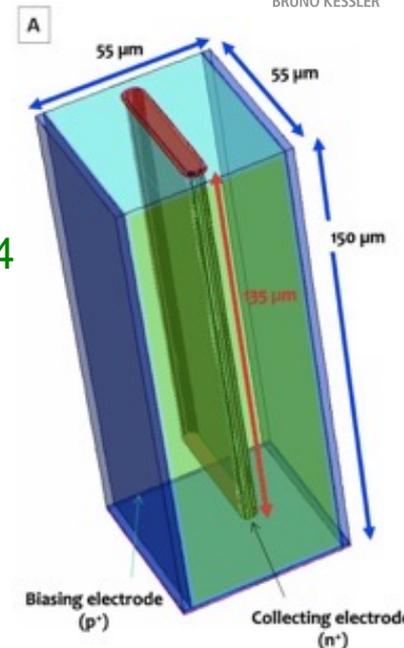
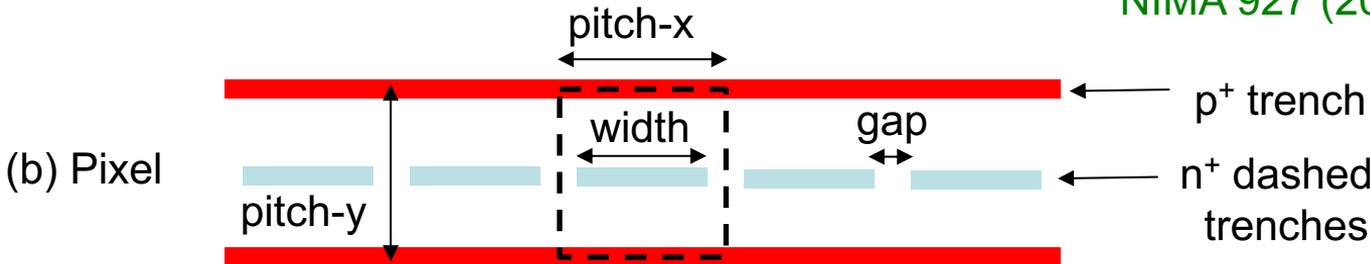


TIME-SPace Operating Tracker (INFN CSN5 Call Project, 2018-2021)

3D-Trenched sensors for tracking + timing have been developed for the first time



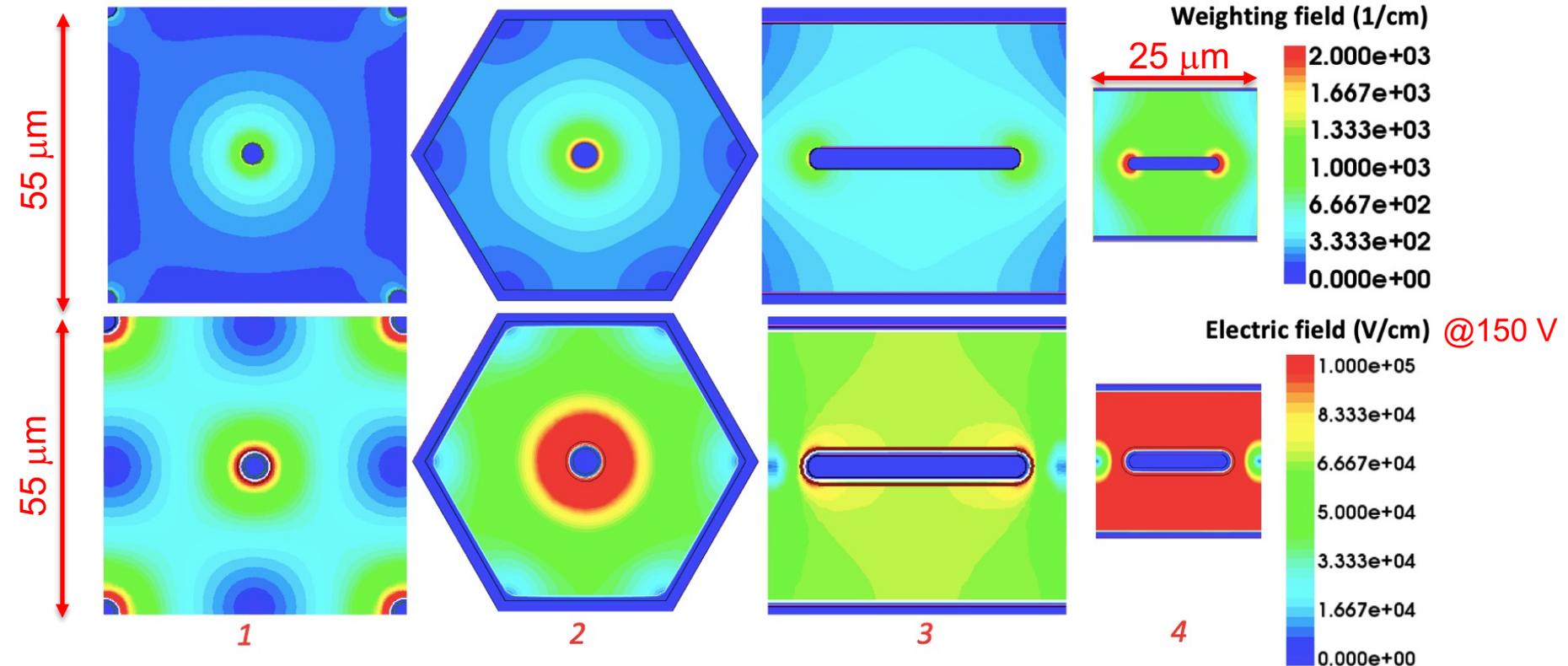
R. Mendicino et al.,
NIMA 927 (2019) 24



- Pixel design was optimized by **simulations**

Simulations (1): TCAD

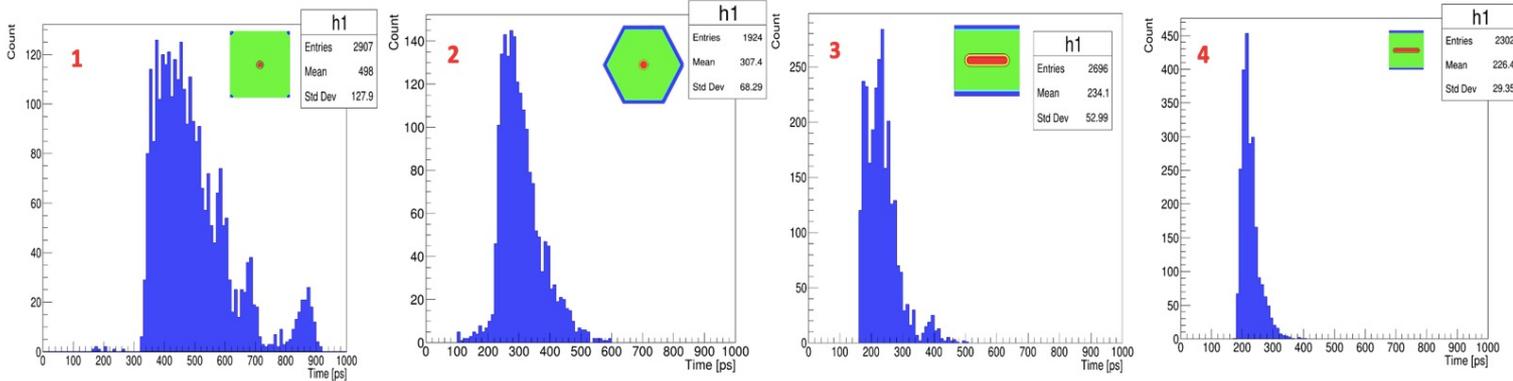
A. Loi , PhD Thesis, Univ. Cagliari, 2020



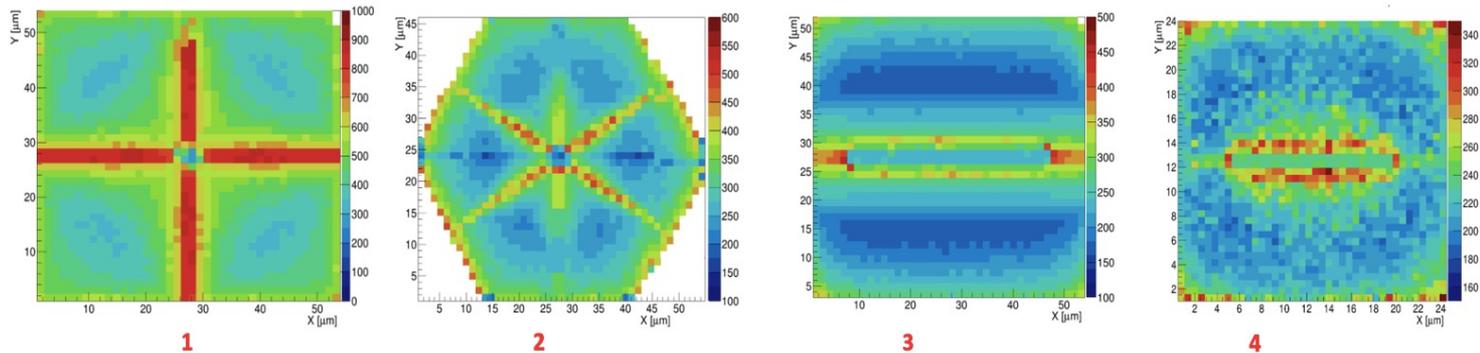
Simulations (2): TCoDe A. Loi et al., JINST 16 (2021) P02011

- Input from TCAD and Geant4, solves drift/diffusion + Ramo current induction

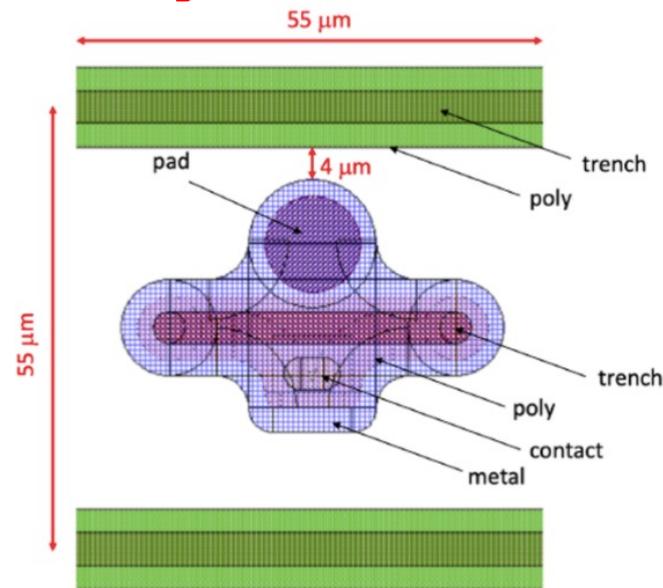
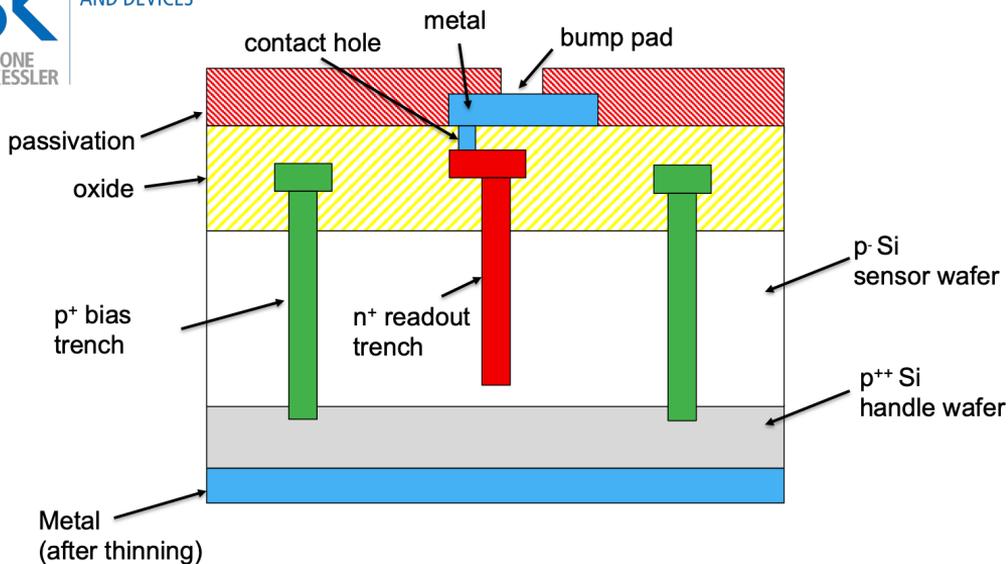
Distributions of charge collection times (ps)



Maps of charge collection times (ps)



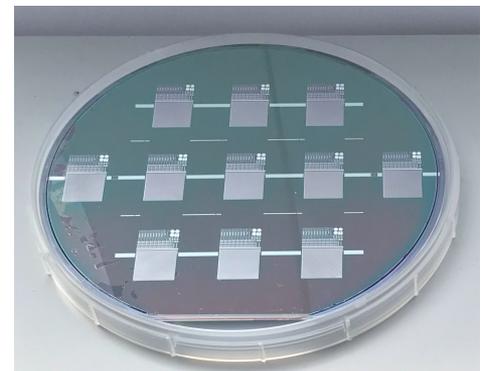
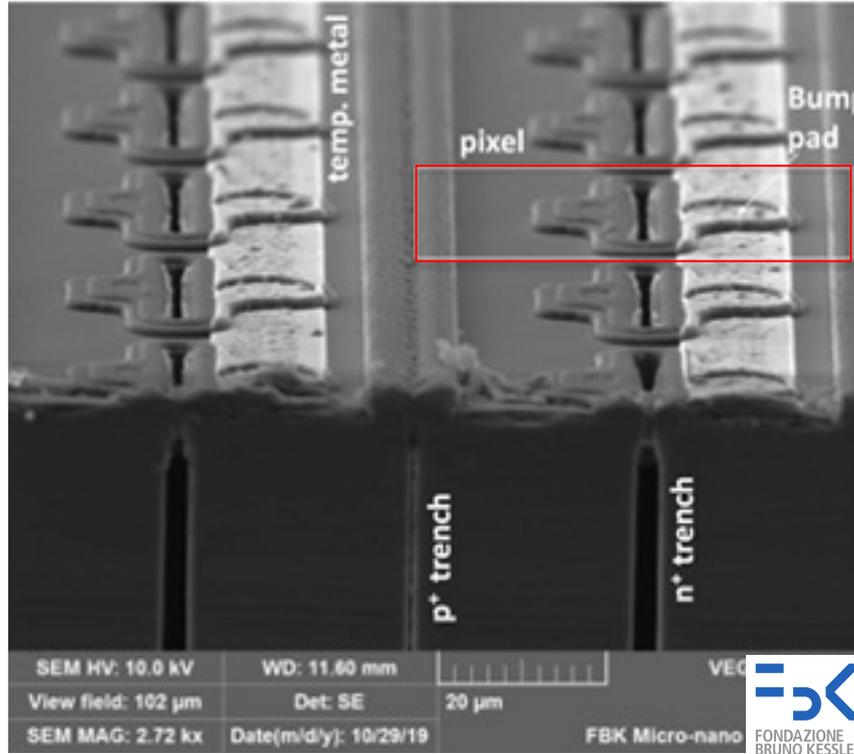
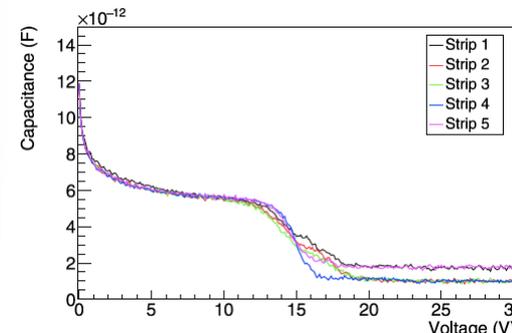
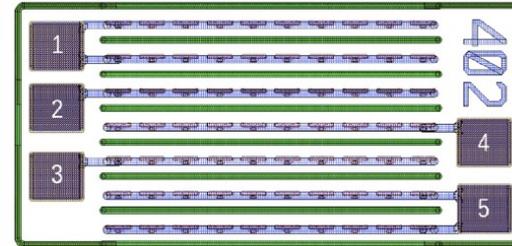
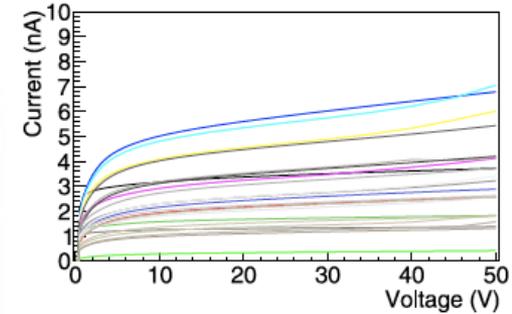
Pixel: from schematic to layout



- FBK adapted to trenches the 3D-column single-sided tech. on SiSi-DWB substrates
- Stepper lithography used for better alignment and detail definition

M. Boscardin et al., *Front. Phys.* 8 (2021) 625275

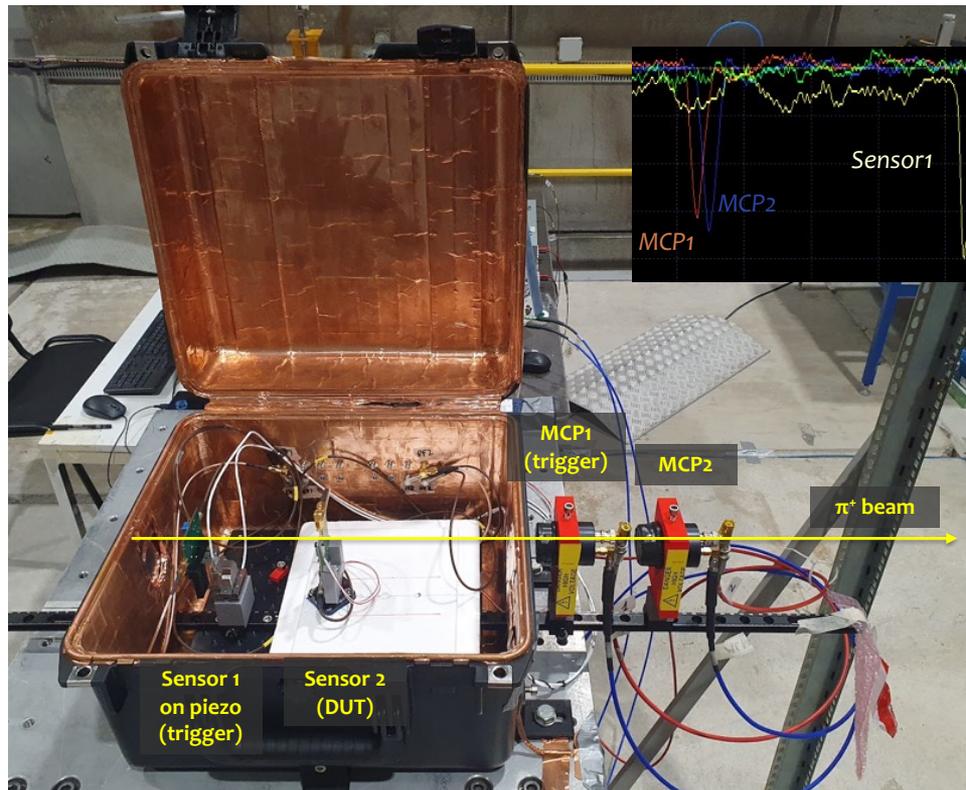
TIMESPOT sensors



Beam test @ CERN SPS/H8 (2021-2022)

π^+ beam, 180 GeV/c

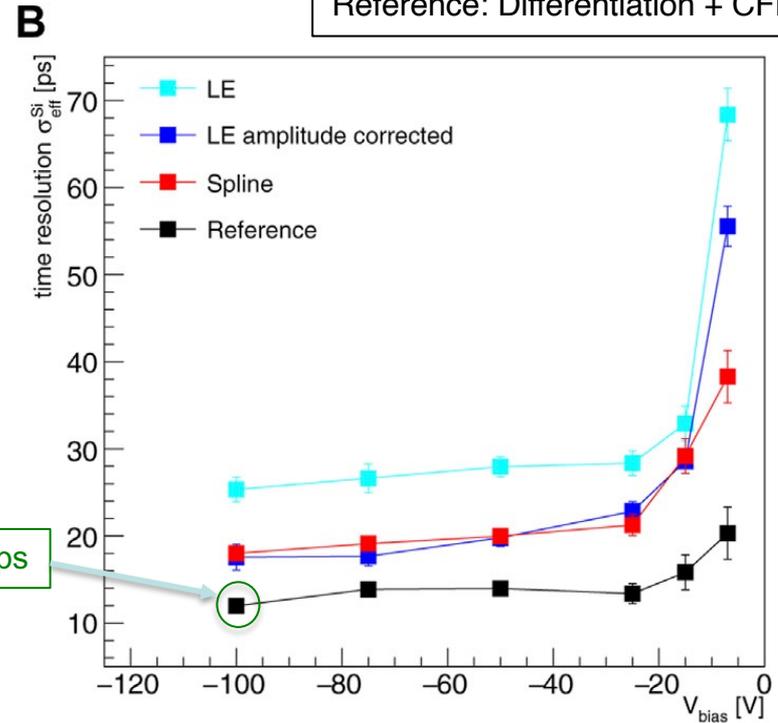
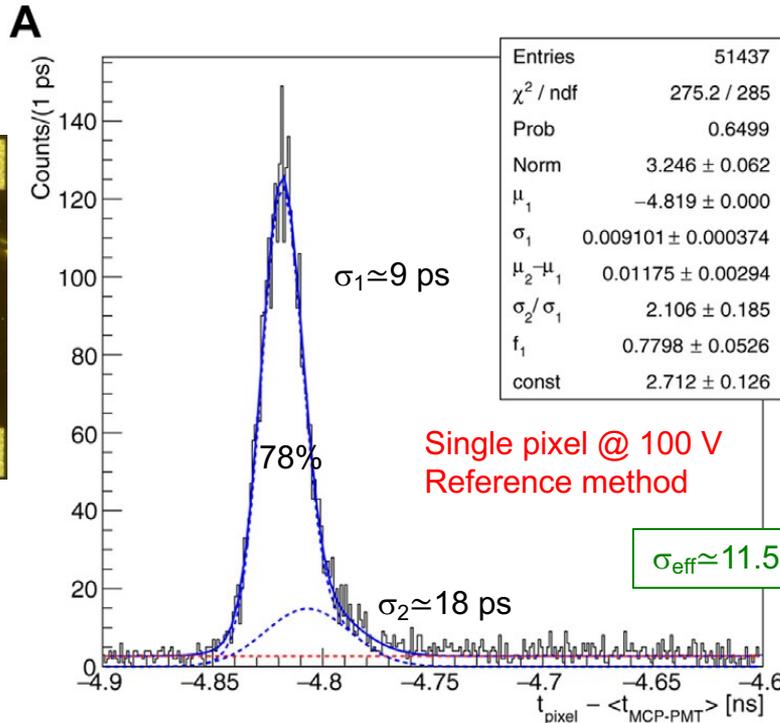
A. Lai, Vertex 2022



- 2 MCP-PMTs on the beam line to time-stamp the arriving particle ($\sigma_{\text{avg}} = 5$ ps)
- Piezoelectric stages to precisely align the two 3D structures with beam, all mounted in a RF-shielded box
- Possibility of operating the fixed sensor down to -40° C using dry ice to test irradiated sensors
- New faster front-end circuit (jitter < 7 ps @ 2fC)
- Readout with an 8 GHz bandwidth 20 GSa/s scope: trigger on the AND of one 3D sensor and one MCP-PMT

Timing measurements (single pixel @ $\alpha_{\text{tilt}}=0^\circ$, not irradi.)

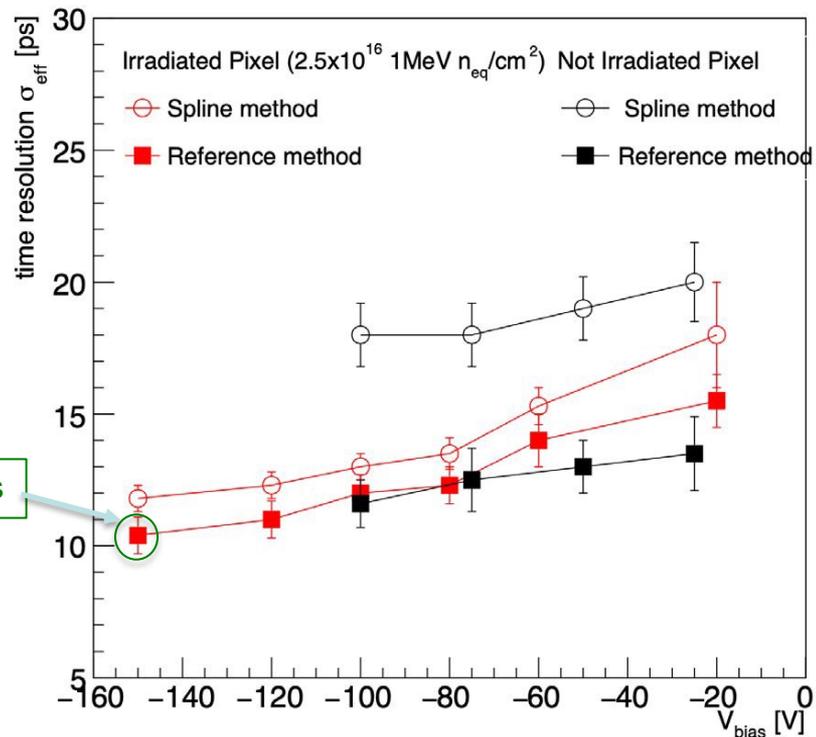
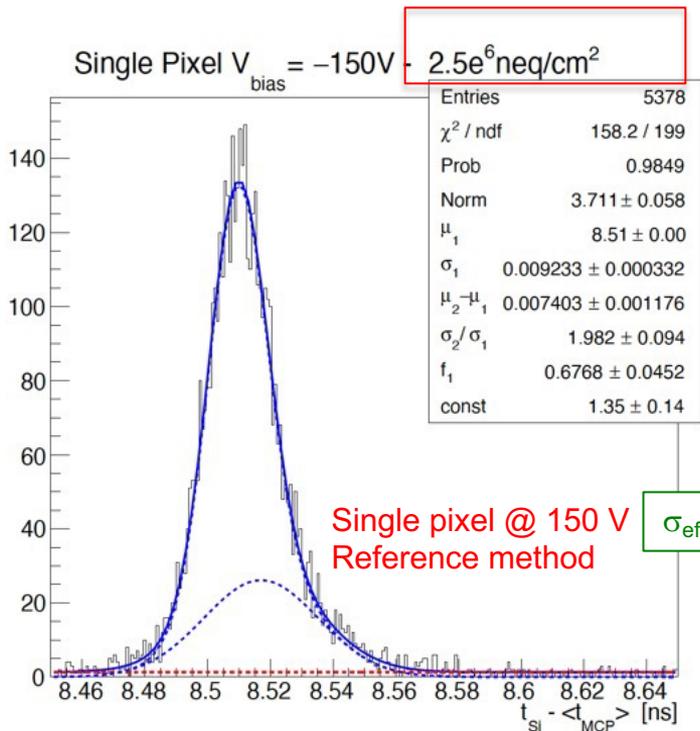
LE: Leading edge, NO ToT correction
LE: Leading edge, ToT correction
Spline: Classic CFD
Reference: Differentiation + CFD



σ_{eff} accounts for the two-gaussian behaviour

F. Borgato et al. Frontiers in Physics 11 (2023) 1117575

Timing measurements (single pixel @ $\alpha_{\text{tilt}}=0^\circ$, irradiated)

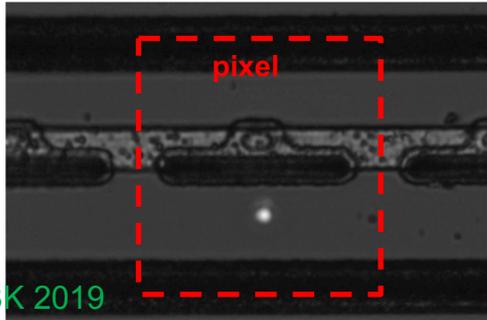


To be compared with $\sim 11 \text{ ps}$ @ 100 V
of the not-irradiated case



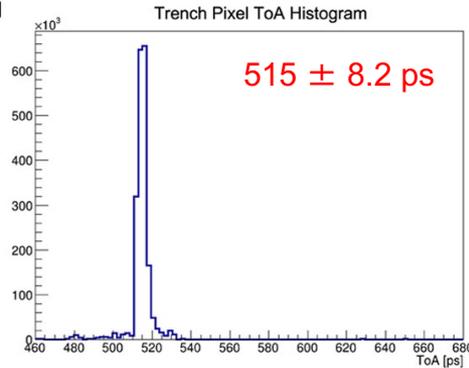
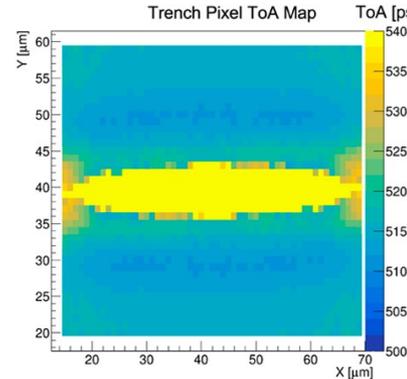
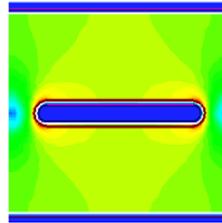
Column vs trench: a direct comparison

IR laser setup (1 mip eq.) , RT, 50 V bias, not irradi.



FBK 2019

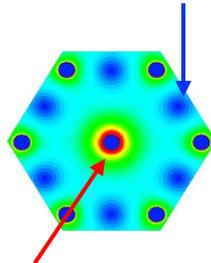
Uniform field



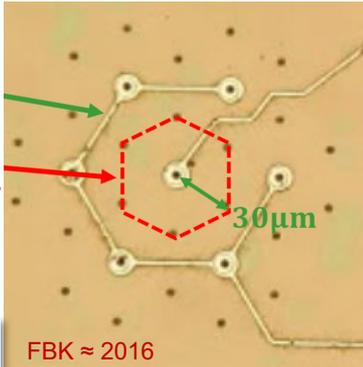
(a)

(b)

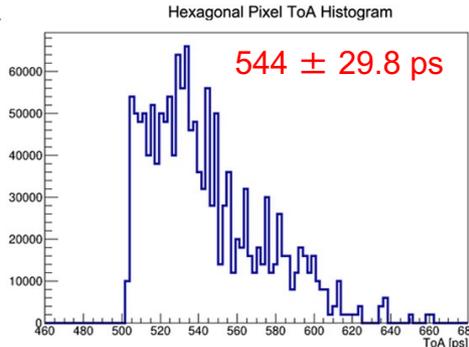
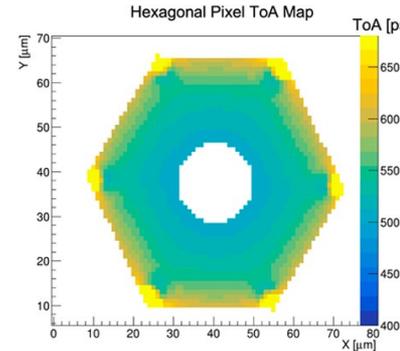
Very slow/inefficient spots
Intrinsically long tails



Super-fast spot not included
(covered by metal)



FBK ≈ 2016



(a)

(b)

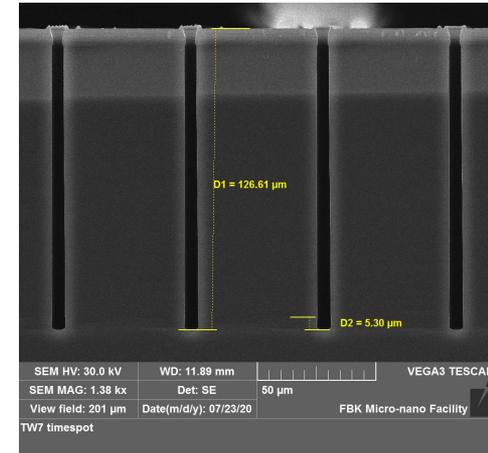
M. Addison et al. NIMA 1054 (2023) 168392



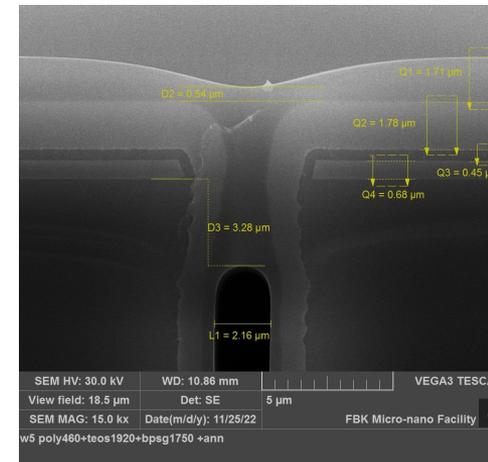
3D-Trench: technological challenges

- 3D-trench technology not yet mature
- Further developments required to:
 - reduce defect density
 - increase device area
 - increase the device density on wafer while reducing the bow
- Main aspects involved:
 - Trench etching
 - Trench filling
 - Planarization
 - Final passivation

DRIE etching of junction trench

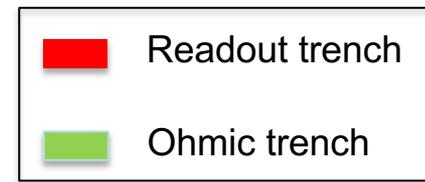
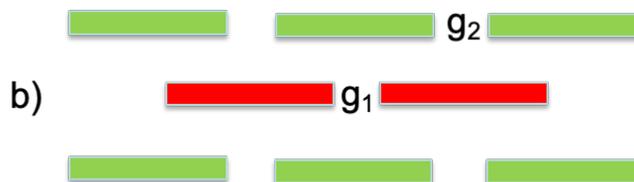
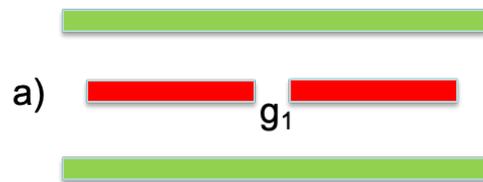


Ohmic trench filling with BPSG (Borophosphosilicate glass)



Alternative layout

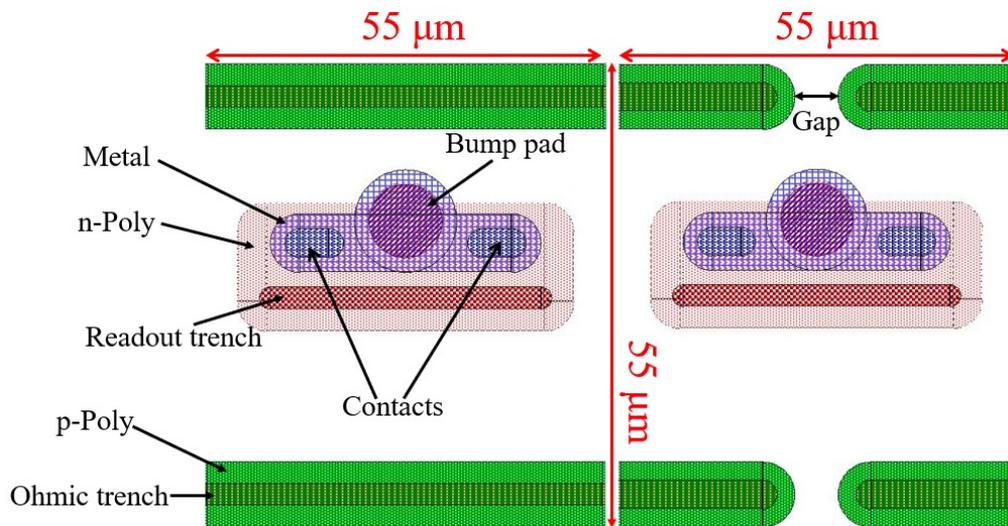
- Continuous ohmic trench (a) vs dashed ohmic trench (b)



New batch funded by

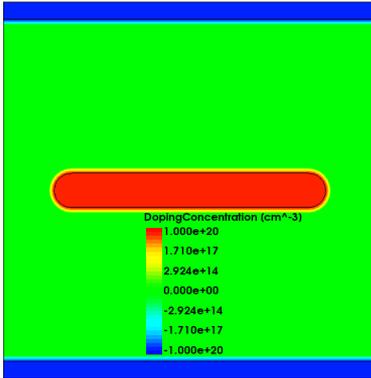


WP6: Hybrid Pixel Sensors for 4D Tracking and Interconnection Technologies

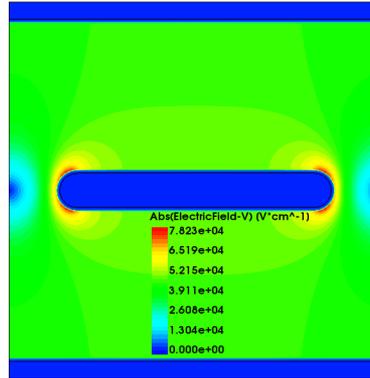


TCAD static simulations

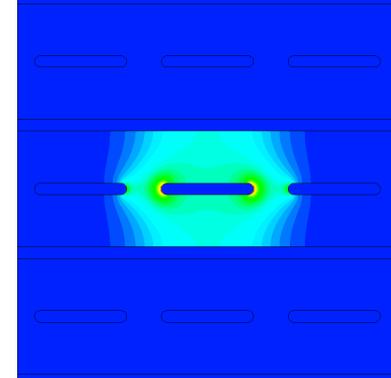
Continuous trench



Doping

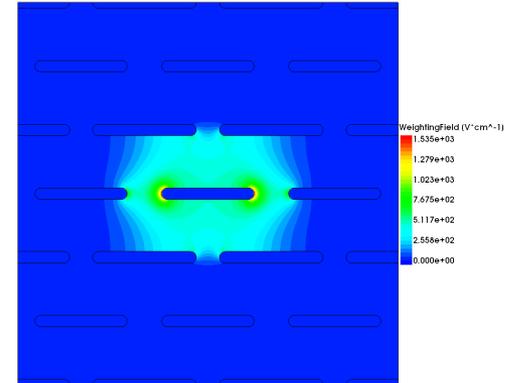
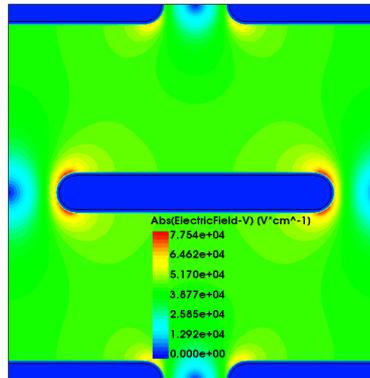
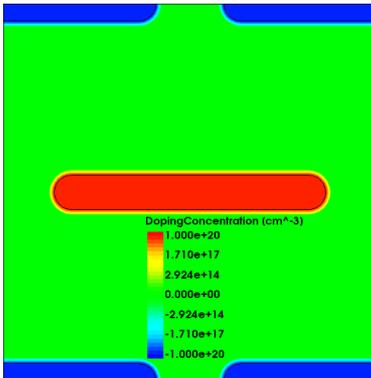


Electric field@100 V

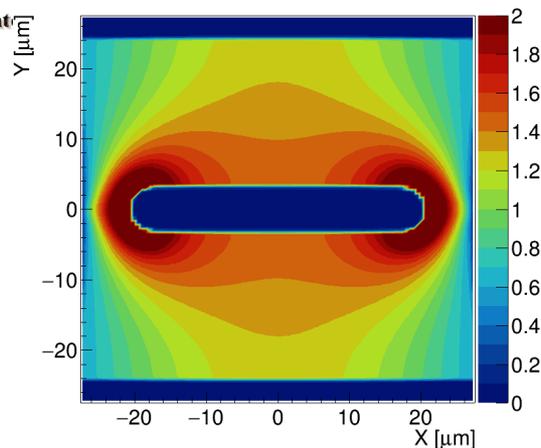


Weighting field

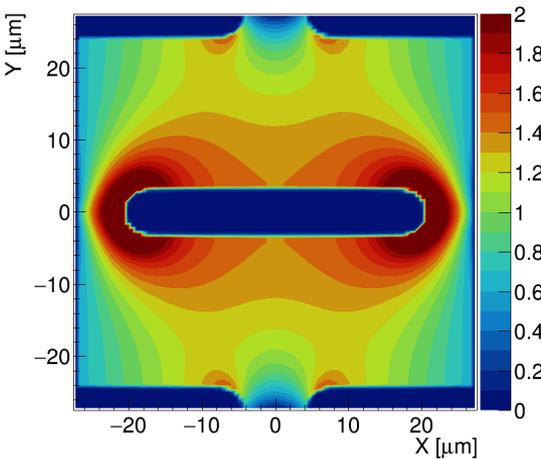
Dashed trench



Continuous trench



Dashed trench



Signal simulations

1) TCAD + Ramo's theorem

$$i_k = -q\vec{v} \cdot \vec{E}_Q$$

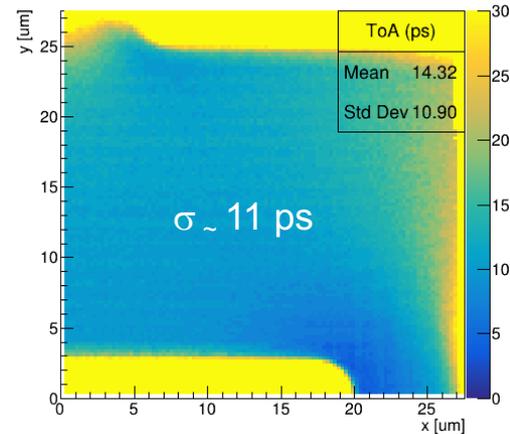
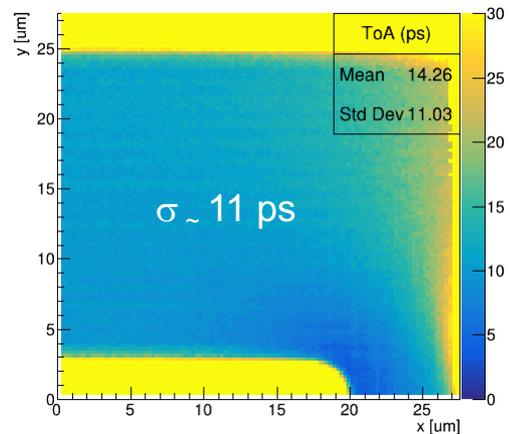
Ramo maps @ 100 V
(induced currents [nA])



2) AllPix² MC simulations

Geant4 (mips) + TCAD input,
Jacoboni-Canali charge transport
Model + default digitizer

ToA [ps] maps @ 100 V
(threshold = 1000 e)



Reticle layout

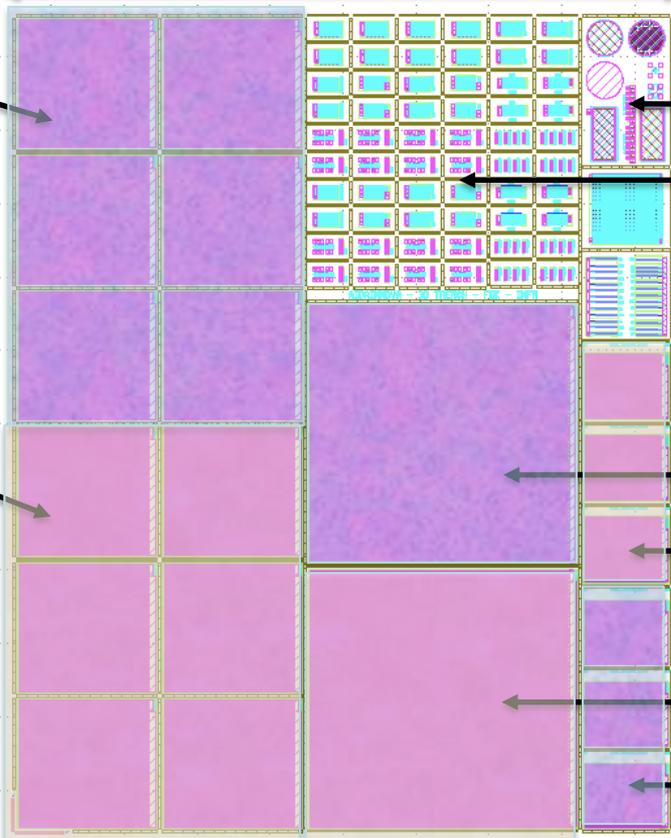


6x Pixels STD
(64x64)

6x Pixels DSH
(64x64)

~22 mm

~18 mm



Technological Test Structures

Device test structures (55 μm pitch and 42 μm pitch, std and dashed)

- Groups of individual pixels
- Strips
- Diodes

1x Pixels STD (128x128)

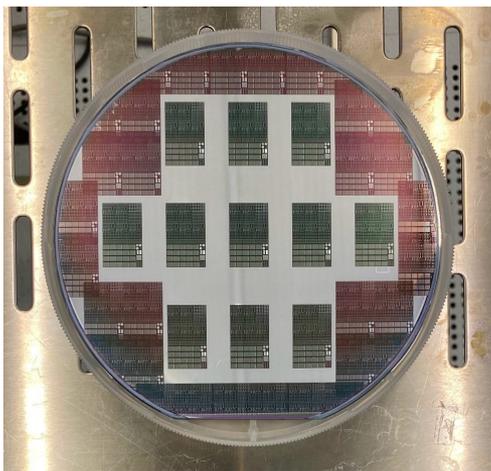
3x Pixels DSH (32x32)

1x Pixels DSH (128x128)

3x Pixels STD (32x32)

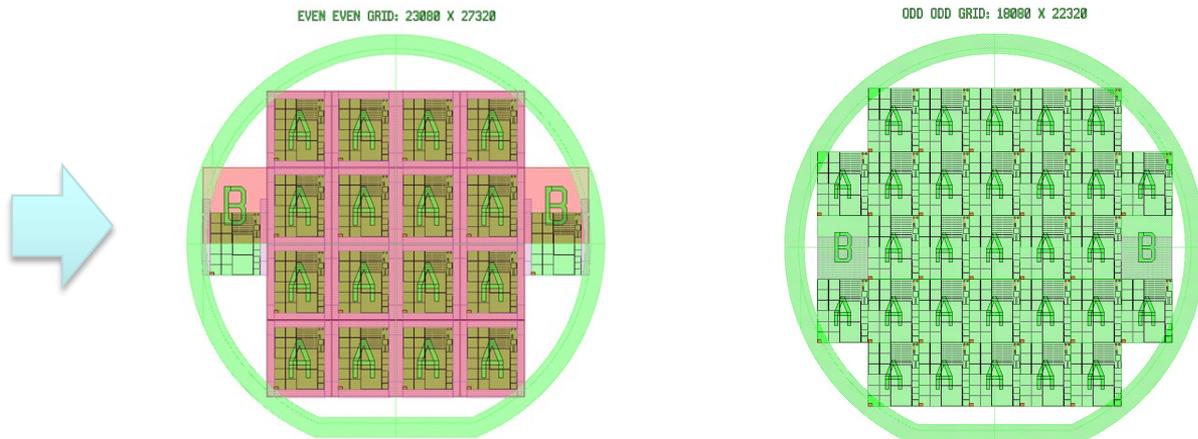
Fabrication at FBK

TIMESPOT batch #2



11 shot exposure

AIDAInnova batch



18 shot exposure

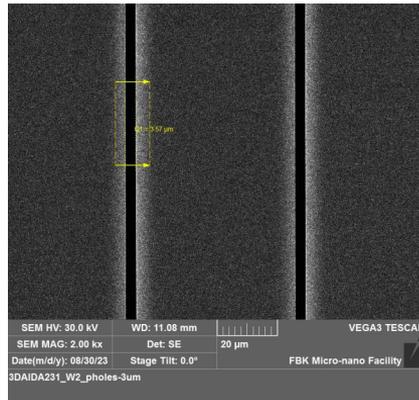
29 shot exposure

- Fabrication under way at FBK, to be completed by Dec. 2023
- Largely increased device density on wafer wrt TIMESPOT batches
- Bow under control (\sim max 20 μ m)

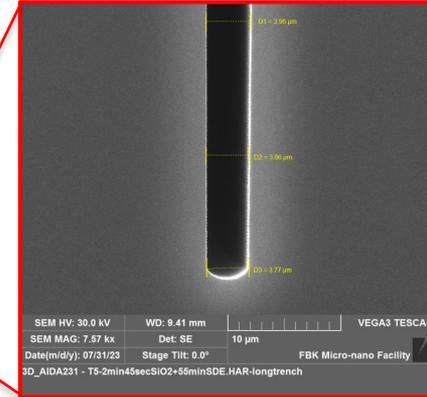
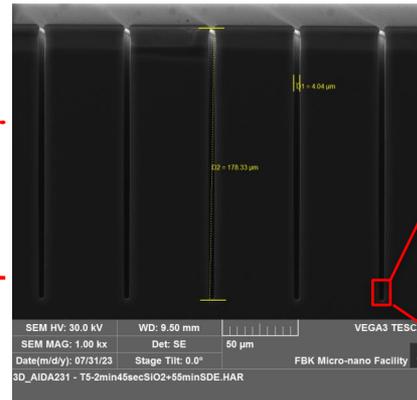
DRIE etching of ohmic trenches

1) Long continuous
ohmic trenches:
3 μm x mm's

Width 3.5 μm

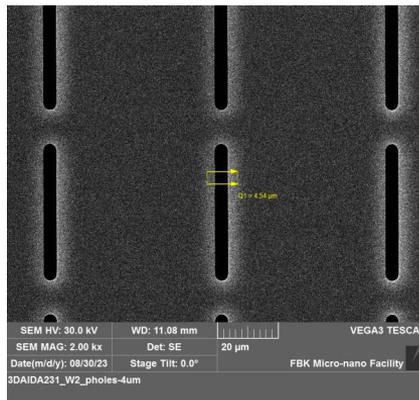


Depth 178 μm

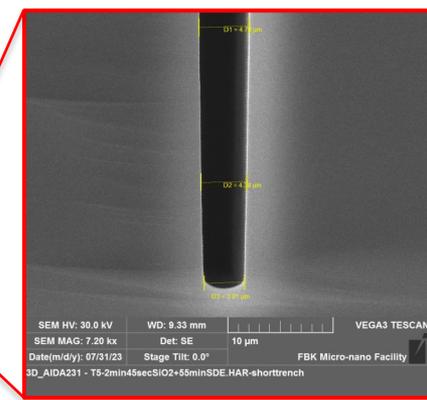


2) Short dashed
ohmic trenches:
4 μm x 40 μm

Width 4.5 μm

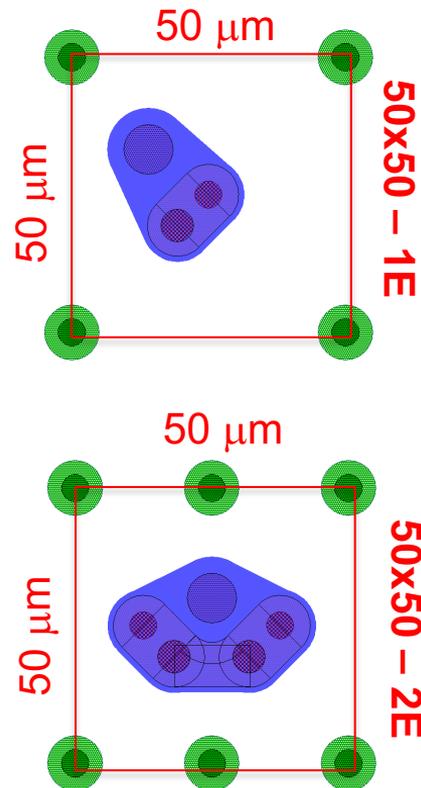


Depth 174 μm



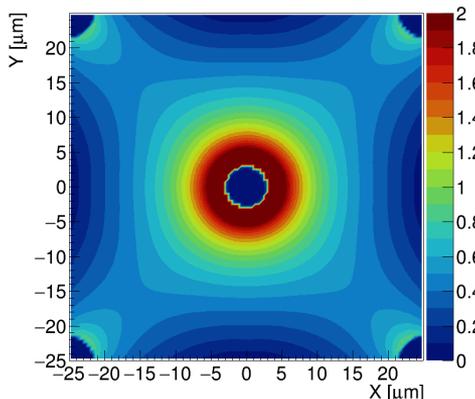
Exploring different 3D-column solutions

- The intrinsic timing resolution of 3D-trench sensors cannot be maintained in pixel implementations, due to the power constraints in the ROC
- 3D-column sensor performance might be good enough for some applications, easing the fabrication
- We are also studying 3D-column designs with different cell size and column arrangement
- These designs will be implemented in a new batch funded by INFN CSN1 (LHCb), to be launched at FBK in January 2024

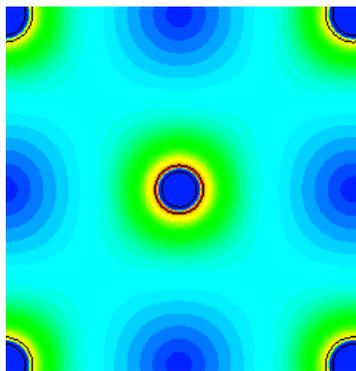


Preliminary comparison of 3D-column designs

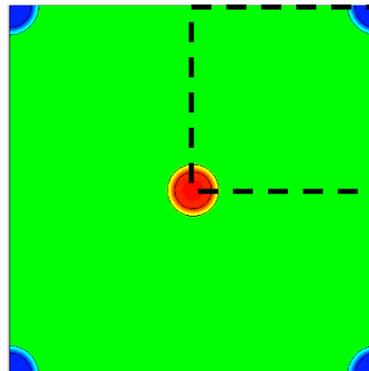
50x50 – 1E



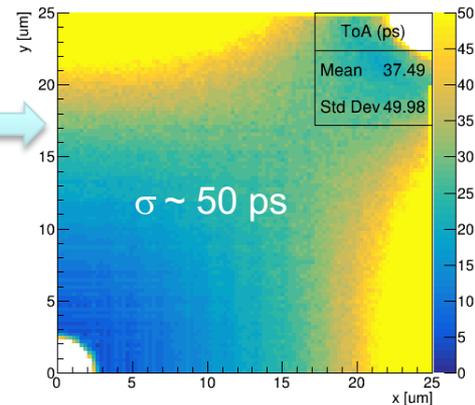
Ramo maps @ 100 V



Electric field @ 100 V

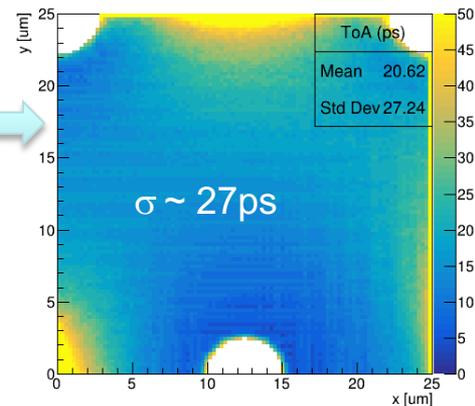
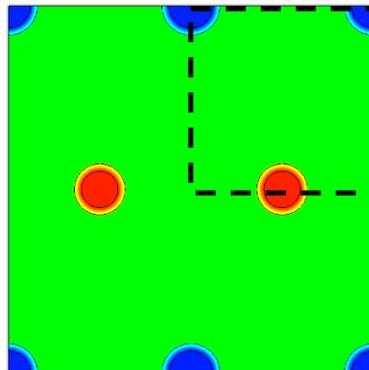
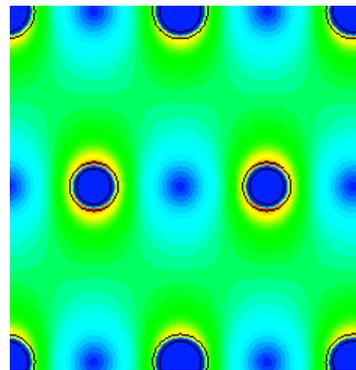
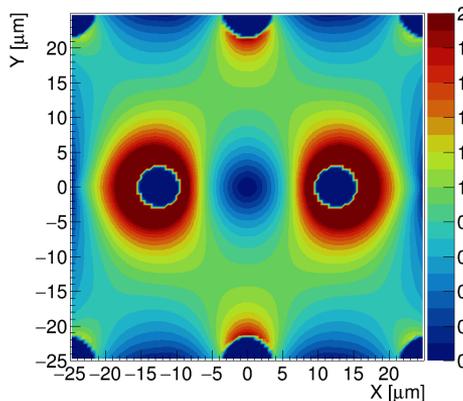


Doping



AllPix² simulations

50x50 – 2E



Conclusions

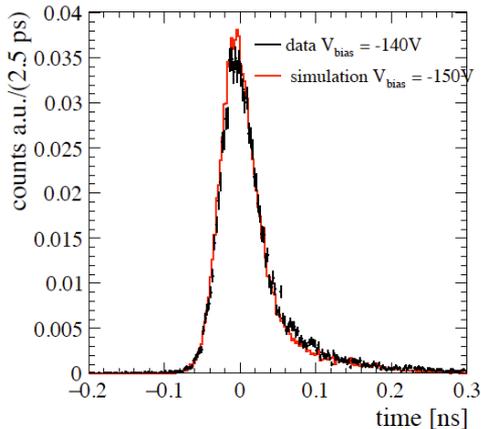
- 3D pixels are a promising candidate for future “tracking+timing” applications
 - Excellent timing resolution so far demonstrated on test structures with discrete, high-speed electronics:
 - ~25 ps for 3D-columnar electrodes
 - ~10 ps for 3D-trenched electrodes
- } Also confirmed after large radiation fluences
- Fabrication technology for 3D-trenched sensors to be optimized for large areas and yield (modified 3D-trench designs might ease fabrication with minimum penalty on the performance)
 - Different 3D-column designs are also worth investigation (trade-off between intrinsic speed and capacitance/noise)

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 - Sherwood Parker for inspiring this work, and Cinzia Da Via (Univ. Manchester, UK) for fruitful discussions

Back Up Slides

Origin of (non-intrinsic) tails



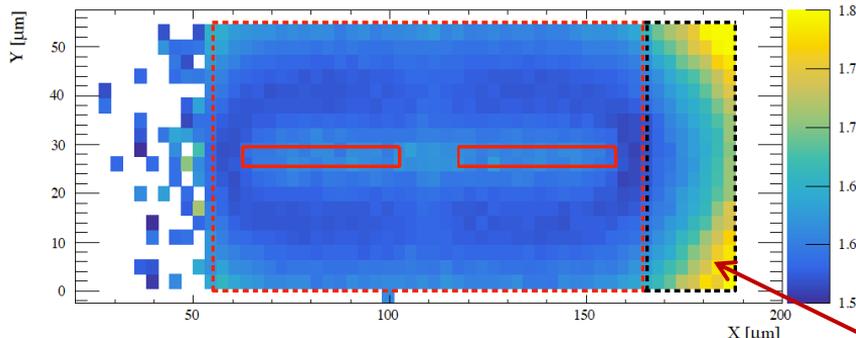
PSI test beam data

Tails have been studied with **very accurate pixel modeling**, from the ionization process to the front-end output (TCode).

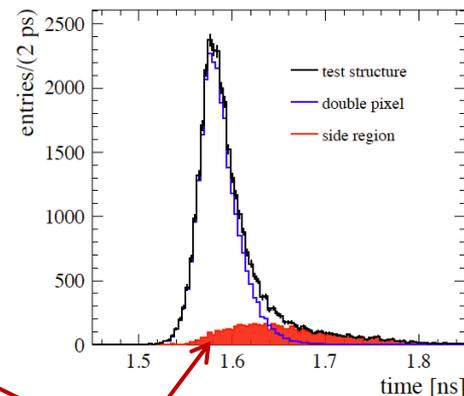
A clear assignation of the tail contribution was done to the **(out)side region** of the pixel (outside the nominal pixel area in this particular case).

Details of this analysis on:

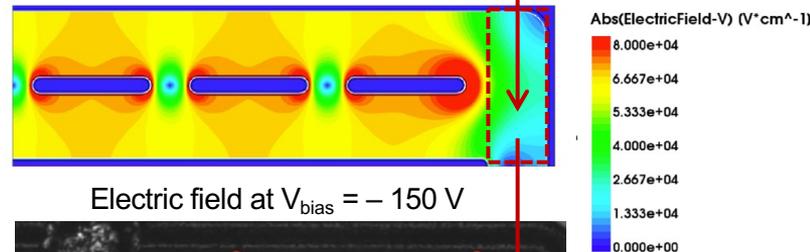
[D. Brundu et al., Accurate modelling of 3D-trench silicon sensor with enhanced timing performance and comparison with test beam measurements. arXiv:2106.08191v2 \[physics.ins-det\], JINST 16 \(2021\) 09, P09028.](#)



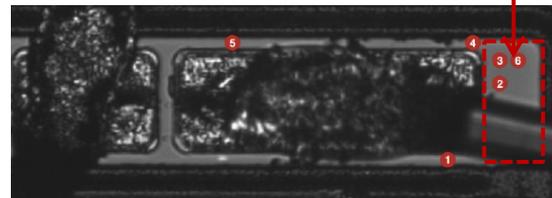
ToA from front-end



side region



Electric field at $V_{bias} = -150$ V



Double pixel picture

Laser test

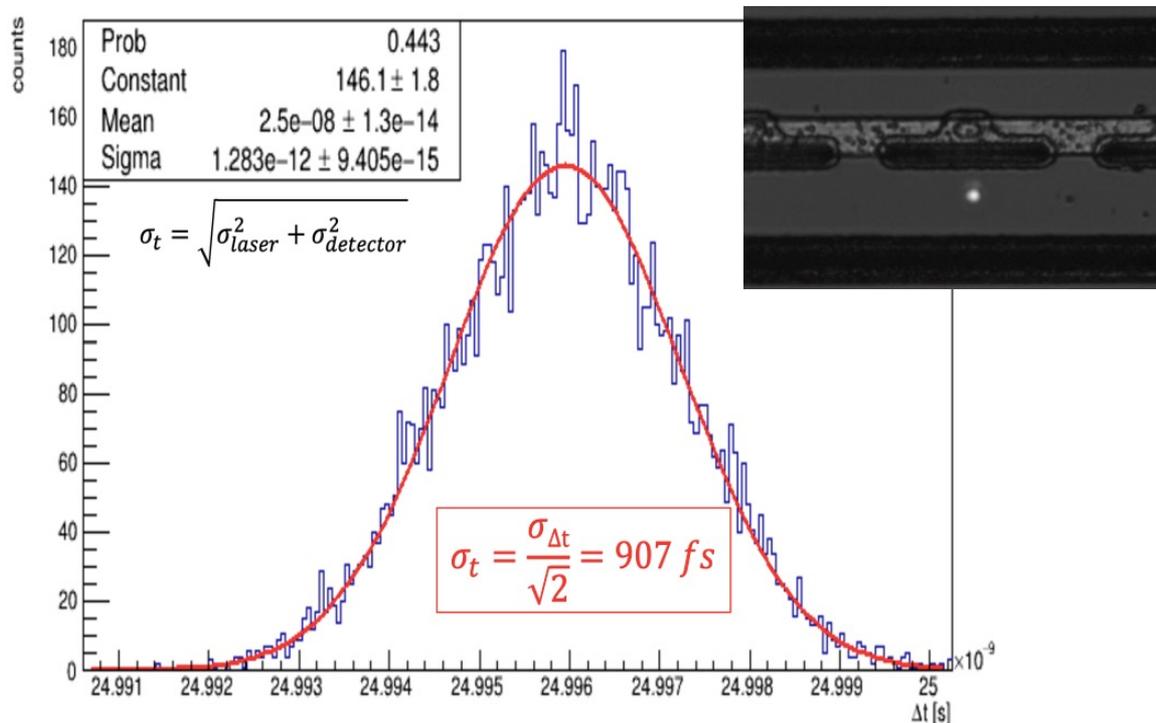
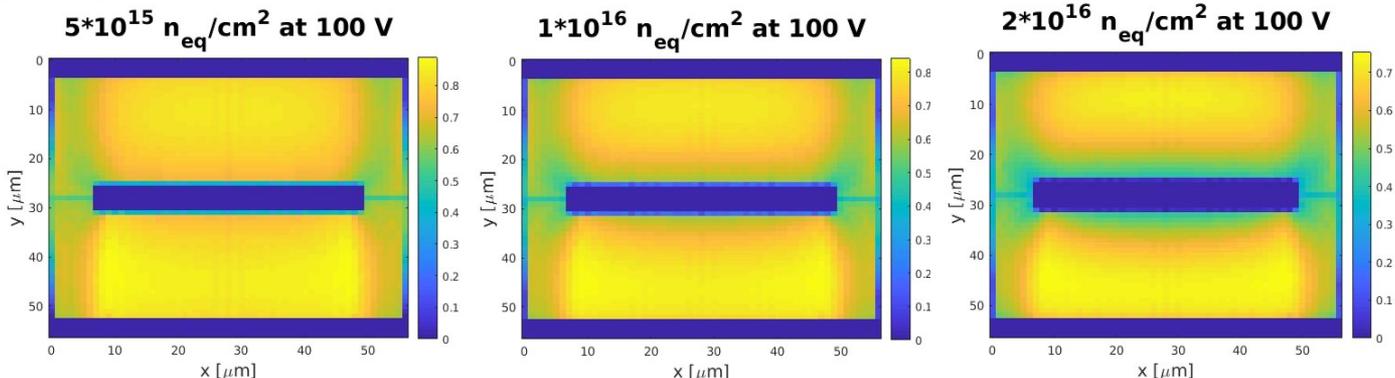


Fig. 3. Time delay measurement between two laser pulses on 3D-trench sensors, used both as time reference and time measuring device. Laser intensity is calibrated to have a 10 MIP equivalent deposit.

3D-trench: radiation hardness

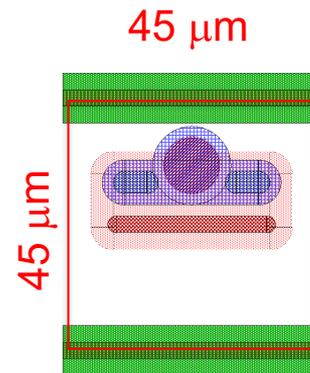
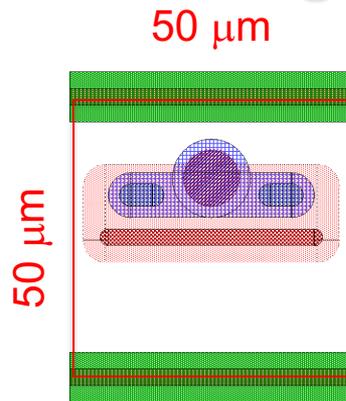
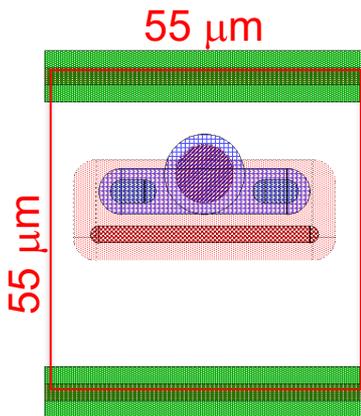
R. Mendicino et al.,
NIMA 927 (2019) 24

- Ramo's Theorem with input from TCAD: $i_k = -q\vec{v} \cdot \vec{E}_Q$
 - ✓ \vec{v} is the **drift velocity** of charge carriers
 - ✓ (Electric field \rightarrow charge trajectory and velocity)
 - ✓ \vec{E}_Q is the **"weighting Field"** \rightarrow charge motion coupling to a specific electrode
 - ✓ Charge trapping included: $Q(t) = Q_0 e^{-t/\tau}$
- New Perugia model (bulk damage) F. Moscatelli et al., IEEE TNS 64 (2017) 2259
- **Very high signal efficiency expected**

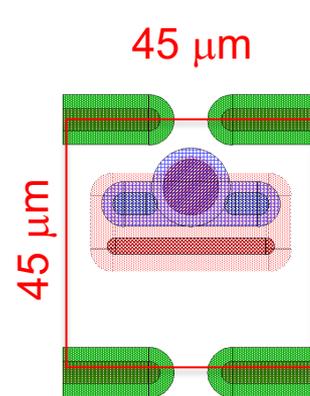
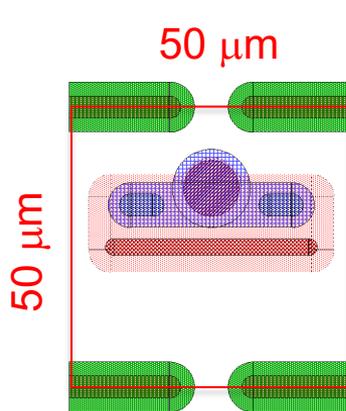
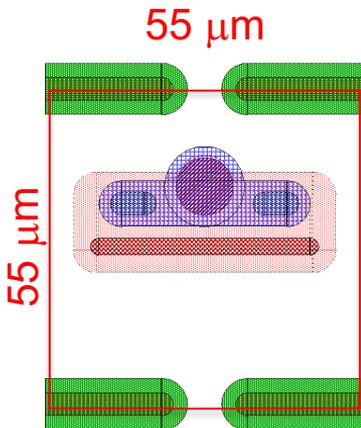


3D-Trench cell scaling

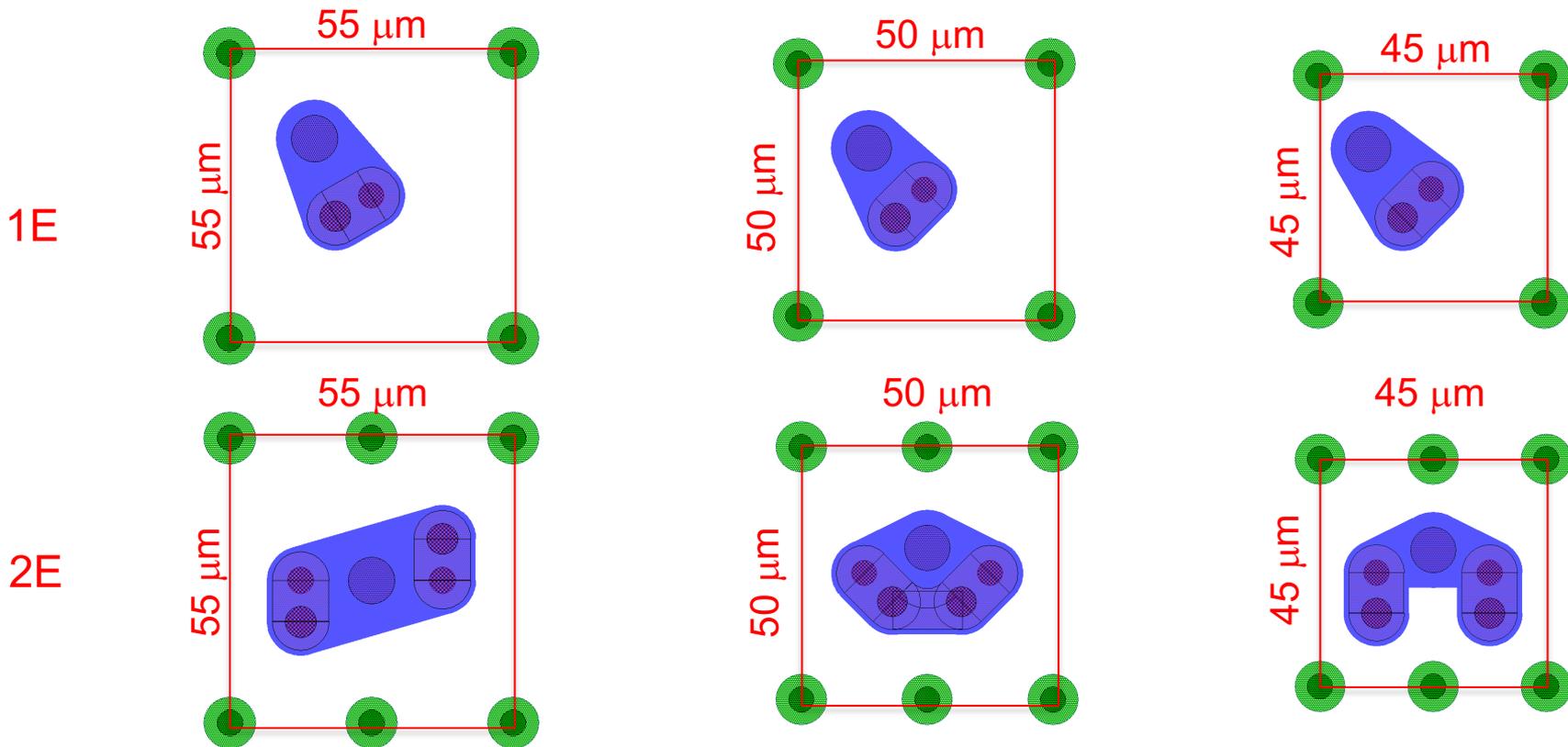
Continuous
Ohmic trench



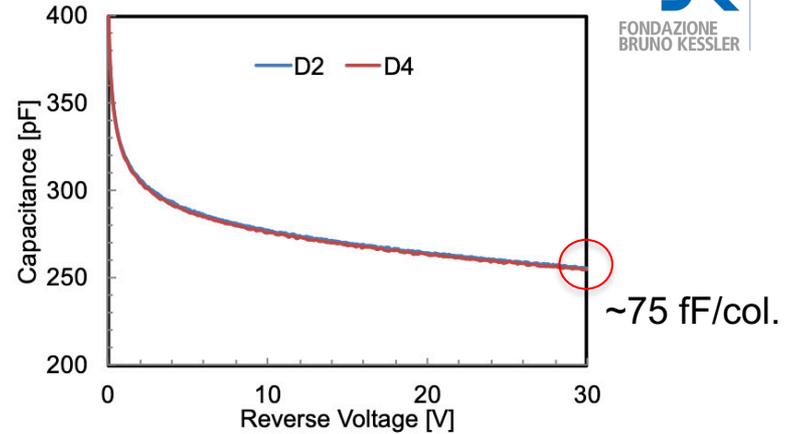
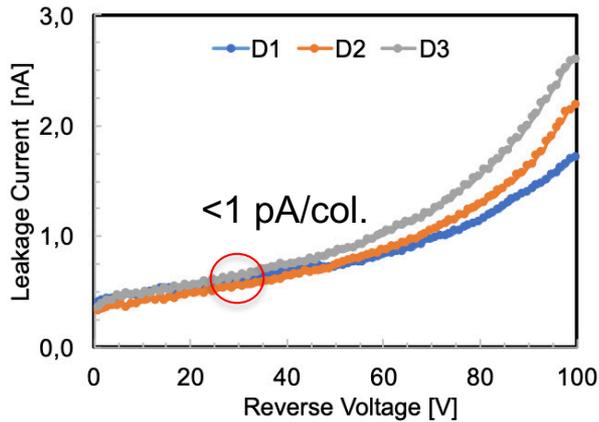
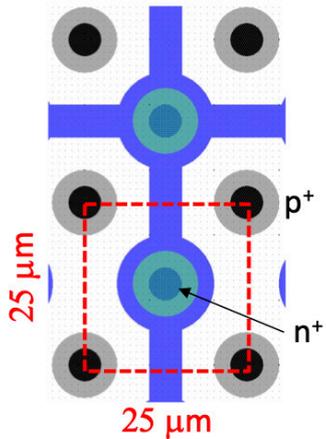
Dashed
ohmic trench



3D-Column cell scaling



Very small-pitch 3D sensors



- Feasibility proved at FBK on 3D diodes with standard process
- Good electrical characteristics
- Additional challenge for pixels would come due to bump pad
- Dedicated effort for technology optimization required

